

1	<b>SUPERRADIANT LASER</b>	38.1	<b>PARTICULAR COMPONENT CIRCUITRY</b>
2	<b>FREE ELECTRON LASER</b>	38.01	.Having feedback circuitry
3	<b>RAMAN LASER</b>	38.02	.For driving or controlling laser
4	<b>LONG WAVELENGTH (E.G., FAR INFRARED)</b>	38.03	.Switch (e.g., thyatron, etc.)
5	<b>SHORT WAVELENGTH LASER</b>	38.04	.Power supply
6	<b>OPTICAL FIBER LASER</b>	38.05	.Electrode
7	<b>THIN FILM LASER</b>	38.06	.Optical pumping
8	<b>LASER LOGIC SYSTEM</b>	38.07	.Controlling current or voltage to laser
9	<b>PARTICULAR BEAM CONTROL DEVICE</b>	38.08	.Having noise suppression circuitry
10	.Q-switch	38.09	.Having fault protection circuitry
11	..Absorption type	39	<b>PARTICULAR ACTIVE MEDIA</b>
12	..Electro-optic	40	.Amorphous (e.g., glass)
13	..Acousto-optic	41	.Insulating crystal
14	..Mechanical	42	..Utilizing color centers
15	...Rotating mirror	43.01	.Semiconductor
16	...Rotating prism	44.01	..Injection
17	..Plural Q-switches	44.011	...Crystal orientation
18	.Mode locking	45.01	...Particular confinement layer
19	.Mode discrimination	45.011	...With strained layer
20	.Tuning	45.012	...With superlattice structure
21	.Nonlinear device	45.013	...With saturable absorption layer
22	..Frequency multiplying (e.g., harmonic generator)	46.01	...Particular current control structure
23	.Producing plural wavelength output	46.011	...Transverse junction
24	.Scanning	46.012	...Channeled substrate
25	.Control of pulse characteristics	46.013	...Having oxidized region
26	.Modulation	46.014	...Having air gap region
27	..Polarization	46.015	...Having implant region
28	..Frequency	46.016	...Disordered region
29.01	.Having particular beam control circuit component	49.01	...Particular coating on facet
29.011	..Feedback circuitry	50.1	...Monolithic integrated
29.012	..Power supply	50.11	...With diffraction grating (Bragg reflector)
29.013	..Having particular electrode structure	50.12	...Laser array
29.014	..Controlling light intensity	50.121	....Multiple wavelength emissive
29.015	..Controlling current or voltage	50.122	....Independently addressable
29.016	..Controlling beam phase	50.123	....Phase locked
29.02	.Optical output stabilization	50.124	....With vertical output (surface emission)
29.021	..Power	50.21	...Having photodetection means
29.022	..Cavity	50.22	...Having an amplifier
29.023	..Phase	50.23	...Having lens
30	..Pulse	51	.Liquid
31	..Amplitude	52	..Chelate
32	..Frequency	53	..Dye
33	<b>PARTICULAR OPERATING COMPENSATION MEANS</b>	54	..Particular structural features
34	<b>PARTICULAR TEMPERATURE CONTROL</b>	55	.Gas
35	.Liquid coolant	56	..Metal vapor
36	.Heat sink	57	..Excimer or exciplex
37	<b>HAVING AN APPLIED MAGNETIC FIELD</b>		

58 ..With means for controlling gas flow  
 59 ..Gas maintenance (e.g., purification, replenishment, etc.)  
 60 ..Including a specified gas additive  
 61 ..Discharge tube feature  
 62 ...Segmented  
 63 ...Backflow feature  
 64 ...Waveguide  
 65 ...Support  
 66 .Active media with particular shape  
 67 ..Disc-shaped  
 68 ..Plural active media or active media having plural dopants  
**69 PARTICULAR PUMPING MEANS**  
 70 .Pumping with optical or radiant energy  
 71 ..End-pumped laser  
 72 ..Pump cavity  
 73 ..High-energy particles  
 74 ...Electron beam  
 75 ..Semiconductor  
 76 ..Plasma  
 77 ..Exploding or combustible material  
 78 ..Heat  
 79 ..Solar  
 80 ..Excited phosphor  
 81 .Electrical  
 82 ..Inductive or capacitive excitation  
 83 ..Transversely excited  
 84 ...Traveling wave  
 85 ..Glow discharge  
 86 ..Having an auxiliary ionization means  
 87 ..Having particular electrode structure  
 88 ...Hollow electrode  
 89 .Chemical  
 90 .Gas dynamic  
 91 .With depopulation of lower states  
**92 PARTICULAR RESONANT CAVITY**  
 93 .Folded cavity  
 94 ..Having a ring configuration  
 95 .Unstable resonator  
 96 .Distributed feedback  
 97 .Plural cavities  
 98 .Specified cavity component

99 ..Reflector  
 100 ..Prism  
 101 ..Lens or lens system  
 102 ..Grating  
 103 ..Window, aperture, and mask  
 104 ...Aerodynamic window  
 105 ..Birefringent material  
 106 ..Polarizer  
 107 .Mirror support or alignment structure  
 108 .Specified output coupling device  
 109 **MISCELLANEOUS**

**CROSS-REFERENCE ART COLLECTIONS**

700 **OPTICAL DELAY**  
 701 **NOZZLE**  
 702 **ISOTOPE**  
 703 **OPTICAL ISOLATER**  
 704 **SUMMARY REFERENCE**  
 705 **NEAT THING**

**FOREIGN ART COLLECTIONS**

FOR 000 **CLASS-RELATED FOREIGN DOCUMENTS**

Any foreign patents or non-patent literature from subclasses that have been reclassified have been transferred directly to FOR Collections listed below. These Collections contain ONLY foreign patents or non-patent literature. The parenthetical references in the Collection titles refer to the abolished subclasses from which these Collections were derived.

**PARTICULAR BEAM CONTROL DEVICE (372/9)**

FOR 100 .Output stabilization (372/29)  
 FOR 101 **WITH PARTICULAR COMPONENT CIRCUITRY (372/38)**  
 FOR 102 .Semiconductor (372/43)  
 FOR 103 ..Injection (372/44)  
 FOR 104 ...Particular confinement layer (372/45)  
 FOR 105 ...Particular current control structure (372/46)

FOR 106 ....Transverse junction (372/47)  
FOR 107 ....Channeled substrate (372/48)  
FOR 108 ...Particular coating on facet  
          (372/49)  
FOR 109 ...Monolithic integrated (372/43)

